

10/669086

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INFORMATION DISCLOSURE STATEMENT BY APPLICANT	ATTY. DOCKET NO. 10901/36	SERIAL NO. To be assigned
	APPLICANT WEIDMANN et al.	
	FILING DATE Herewith	GROUP 287Z To be assigned

## U. S. PATENT DOCUMENTS

EXAMINER INITIAL	PATENT NUMBER	PATENT DATE	NAME	CLASS	SUBCLASS	FILING DATE*
<i>JD</i>	4,536,650*	Aug. 20, 1985	Carena et al.	250	231.14	—
<i>JD</i>	4,644,156**	Feb. 17, 1987	Takahashi et al.	216	24	—

\* - If pertinent

\* Cited in the attached German Search Report (copy enclosed).

\*\* Copy of reference is not enclosed because reference is cited in Search Report (copy of reference provided by International Searching Authority).

## FOREIGN PATENT DOCUMENTS

EXAMINER INITIAL	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
						YES	NO
<i>JD</i>	40 06 789	Sept. 5, 1991	Germany			NO Abs., *	
<i>JD</i>	34 17 176	Nov. 21, 1985	Germany			NO Abs., *	
<i>JD</i>	34 16 864	Nov. 21, 1985	Germany			NO Abs., *	
<i>JD</i>	32 19 917	Dec. 23, 1982	Germany			NO Abs., *	
<i>JD</i>	0 240 776	Oct. 14, 1987	Europe			NO Abs., *	
<i>JD</i>	43 20 728	Jan. 12, 1995	Germany			NO **	
<i>JD</i>	0 511 597	Nov. 4, 1982	Europe			**	
<i>JD</i>	0 849 567	Jun. 24, 1998	Europe			NO **	
<i>JD</i>	2 072 850	Oct. 7, 1981	Europe			**	

\* Cited in the attached German Search Report.

\*\* Copy of reference is not enclosed because reference is cited in Search Report (copy of reference provided by International Searching Authority).

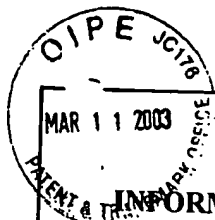
## OTHER DOCUMENTS

EXAMINER INITIAL		AUTHOR, TITLE, DATE, PERTINENT PAGES, ETC.
<i>JD</i>	—	Zubel, I. et al., "Silicon anisotropic etching in alkaline solutions I. The geometric description of figures developed under etching Si(100) in various solutions," Sensors and Actuators A, vol. 70, no. 3, 1998, pp. 250-259.**
<i>JD</i>	—	Zubel, I. et al., "Silicon anisotropic etching in alkaline solutions II. On the influence of anisotropy on the smoothness of etched surfaces," Sensors and Actuators A, vol. 70, no. 3, 1998, pp. 260-268.**

\*\* Copy of reference is not enclosed because reference is cited in Search Report (copy of reference provided by International Searching Authority).

EXAMINER <i>Zahy Zubel</i>	DATE CONSIDERED 6 DEC 2004
EXAMINER: Initial if citation considered, whether or not citation is in conformance with M.P.E.P. 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.	

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<b>INFORMATION DISCLOSURE STATEMENT BY APPLICANT</b>	ATTY. DOCKET NO. 10901/36	SERIAL NO. 10/069,086
	APPLICANT J. Weidmann et al.	
	FILING DATE July 8, 2002	GROUP 2877 2872

U. S. PATENT DOCUMENTS

EXAMINER INITIAL	PATENT NUMBER	PATENT DATE	NAME	CLASS	SUBCLASS	FILING DATE*

FOREIGN PATENT DOCUMENTS

EXAMINER INITIAL	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
						YES	NO

OTHER DOCUMENTS

EXAMINER INITIAL		AUTHOR, TITLE, DATE, PERTINENT PAGES, ETC.
<i>JS</i>	—	Petersen, Kurt E., "Silicon As A Mechanical Material", Proceedings of the IEEE, U.S., IEEE, NY, Bd. 70, No. 5, May 1, 1982, pp.420-457*

\* Listed in International Search Report (copy not provided, copy provided by International Searching Authority).

EXAMINER <i>John Zuba</i>	DATE CONSIDERED 6 DEC 2004
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